

PATENT

U.S. UTILITY Patent Application

MS O.I.P.E.

EXAMINER

APPLICATION NO.	CONT/PRIOR	CLASS	SUBCLASS	ART UNIT	EXAMINER
09/805273	D	438	786	283	Cotrada

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APPLICANTS
TITLE

Highly conductive semiconductor structures, method of forming same via plasma etch, and electrical devices incorporating highly conductive semiconductor structures

PTO-2040
12/90